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THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Daniel R. Caldwell, et al.

Docket No: TI-36721

Serial No: 10/706,762

Conf. No: 7834

Examiner: Dung V. Nguyen

Art Unit: 3723

Filed: 11/10/2003

For: CHEMICAL MECHANICAL POLISHING SLURRY PUMP MONITORING SYSTEM AND METHOD

AMENDMENT UNDER 37 C.F.R. § 1.111

Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

MAILING CERTIFICATE UNDER 37 C.F.R. §1.8(a)

I hereby certify that the above correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on 1-5-05.

Ann Trent
Ann Trent

Dear Sir:

Responsive to the Office Action mailed October 14, 2004, in connection with the above identified application, Applicants respectfully submit the following remarks.